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10836 U.S. PTO  
09/605293  
06/28/00

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of

Applicant : David L. Chapek

Title : METHOD FOR CONTROLLING THE MORPHOLOGY OF  
DEPOSITED SILICON ON A SILICON DIOXIDE SUBSTRATE  
AND SEMICONDUCTOR DEVICES INCORPORATING SUCH  
DEPOSITED SILICON

Docket : MIO 0037 VA

**BOX PATENT APPLICATION**

Assistant Commissioner for Patents  
Washington, D.C. 20231

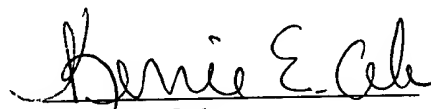
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Date of Deposit June 28, 2000

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Kerrie E. Cela  
Legal Secretary